## Non-Destructive Surface Analysis of Materials by MeV Ion Beams, Microscopy and Computer Simulation

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Material analysis, especially surface analysis of materials, has been increasingly important. A wide range of surface analysis techniques is available, involving e.g. ion, electron and photon beams interacting with a solid target. The techniques are, generally, complementary and provide target information for near surface depths. Nuclear techniques, which are essentially non-destructive, provide for analysis over a few microns giving absolute values of concentrations of isotopes and elements. Applications have been given in a variety of areas such as scientific, technologic, industry, arts and medicine, using low energy MeV ion beams [1-7]. Nuclear reactions make it possible tracing of isotopes with high sensitivities. We use ion-ion reactions and the energy analysis method. At a suitably chosen energy of the incident ion beam, an energy spectrum is acquired of ions arising from nuclear events, occurring at successive depths in the target.  $\Theta_L$  is the laboratory detection angle and  $\Theta_R$  is the target rotation angle. Such spectra are simulated and compared with experimental data, giving target composition and concentration profile information [4-7]. Elastic scattering is a particular and important case. In this context a computer program has been developed, mainly for flat targets [4-6]. The non-flat target situation arises as an extension.

Successful applications of the method are given using the  $^{18}\text{O}(p,\alpha_0)^{15}\text{N}$  reaction and elastic scattering of  $(^4\text{He})^+$  ions for three types of samples. Scanning electron microscopy (SEM) is used as a complementary technique. Experimental details have been given [4]. The samples used for acquisition of charged particle spectra were: 1) S1 was obtained by high temperature oxidation of austenitic steel in C  $^{18}\text{O}_2$  gas. Weight gain measurements had given a 4.2 µm thick oxide. A uniform concentration profile of  $^{18}\text{O}$  was expected. SEM has shown a reasonably flat oxide (Fig. 1). 2) S2, a thick flat sample of sapphire (Al<sub>2</sub>O<sub>3</sub>). Uniform distributions of Al and O were expected in the sapphire substrate. 3) S3, a thick flat sample of zinc sulphide (ZnS). Uniform distributions of Zn and S were expected in the sample substrate. Spectral data were obtained from: 1) S1, using the  $^{18}\text{O}(p,\alpha_0)^{15}\text{N}$  reaction at E<sub>p</sub>=1.78 MeV, an energy slightly above the resonance energy at 1.766 MeV in the differential cross section, and  $\Theta_L$ =165°. 2) S2, using a ( $^4\text{He}$ )<sup>+</sup> ion beam at E<sub>a</sub>=1.5 MeV,  $\Theta_L$ =165°. 3) S3, using a ( $^4\text{He}$ )<sup>+</sup> beam at E<sub>a</sub>=3.1MeV,  $\Theta_L$ =165°.

Published nuclear data, namely for reaction differential cross section and stopping power, were used in the computer predictions. Good fits to experimental data were obtained. For S1, a uniform concentration profile of  $^{18}$ O was found with  $X_1$ =4.4  $\mu$ m. This value is close to the expectation and higher than the determination made by the resonance method of analysis using the 1.766 MeV resonance, as the present method presents a higher depth resolution. Details of the fit are shown in Fig. 2. For S2, uniform concentration profiles were used with  $X_1$  parameters of 0.53 and 0.23  $\mu$ m for Al and O, respectively. Details of the fit are shown in Fig. 3. For S3, uniform concentration profiles were used with  $X_1$  parameters of 2.5 and 1.5  $\mu$ m for Zn and S, respectively. Details of the fit are shown in Fig. 4.

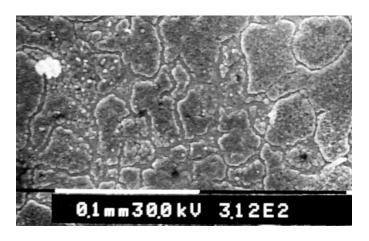
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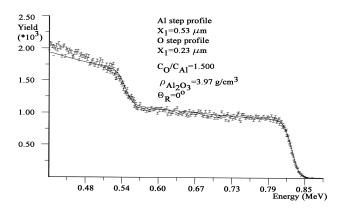
The present work shows that the combined use of nuclear techniques and SEM microscopy is a highly powerful analytical tool for surface analysis of materials [8].

## References:

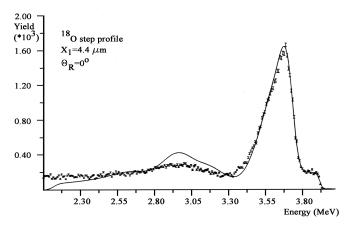
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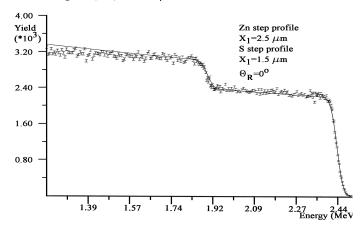
**Figure 1**. SEM image of the oxidized steel sample (S1).



**Figure 3.** Computed fit to the elastic scattering data from the sapphire target, (S2), for  $E_{\alpha}=1.5$  MeV,  $\Theta_L=165^{\circ}$ .



**Figure 2.** Computed fit to data of the  $^{18}\text{O}(\text{p},\alpha_0)^{15}\text{N}$  reaction from the oxidized steel target, (S1), for  $E_p=1.78$  MeV,  $\Theta_L=165^\circ$ .



**Figure 4.** Computed fit to the elastic scattering data from the ZnS target, (S3), for  $E_0$ =3.1 MeV,  $\Theta_L$ =165°.